



**REQUEST FOR EXTENSION
OF TIME PURSUANT TO
37 C.F.R. § 1.136(a)**

Docket Number:

10191/1614

Conf. No.:

3872

Application Number
09/720,720

Filing Date
February 28, 2001

Reissue Examiner
Binh TRAN

Art Unit
3872

Invention Title

**METHOD FOR ELIMINATING DEFECTS
IN SILICON ELEMENTS THROUGH
SELECTIVE ETCHING**

Inventor:

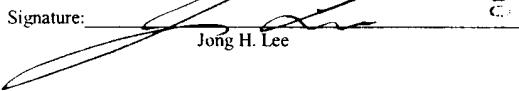
Richard SPITZ et al.

Commissioner for Patents
Washington D.C. 20231

I hereby certify that this correspondence is being deposited with the
United States Postal Service as first class mail in an envelope addressed
to: Commissioner for Patents, Washington, DC 20231.

Dated: January 28, 2003

Reg. No. 36,197

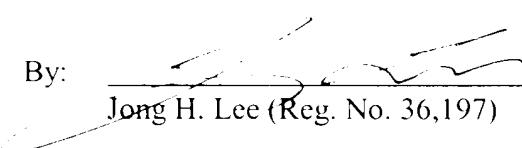
Signature: 
Jong H. Lee

Applicants respectfully request a one-month extension of time in which to respond to the office action dated October 1, 2002 for which a response period expiring on January 1, 2003 was set. The extended period expires on February 1, 2003.

1. The Commissioner is hereby authorized to charge payment of the 37 C.F.R. § 1.136(a) extension fee of \$110.00 to the Deposit Account of **Kenyon & Kenyon**, Deposit Account number **11-0600**. The office is also authorized to charge any additional fees, or credit overpayments, associated with this paper to Deposit Account **11-0600**.
2. A duplicate copy of this form is enclosed.

Dated: January 28, 2003

By:


Jong H. Lee (Reg. No. 36,197)

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